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U.S. Department of Commerce, Patent and Trademark Office					Att	y Docket N	lo.	Serial No.		
					M-15319 US			101758,989		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant(s)					
(Use several sheets if necessary)					Yin S. Tang					
					Filing Date			Group	Group	
					Ō	1/16/2	2004	287	2873	
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*Examiner		Document		T				Filing I		
Initial	 	Number	Date	Name		Class	Subclass	If Appro	priate	
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	AG								1.	
	AH	·								
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)										
as	AI B. Volckaerts et al., The Fabrication of Cylindrical Micro-Lens Arrays with Deep Lithography with Protons, Cyclotron Department VUB, Laarbeeklaan 103, 1090 Brussels, Belgium									
AJ DAVID SPECTOR PRIMARY EXAMINER										
Examiner Date Considered 5/11/2005										
	*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through									
citation if not in conformance and not considered. Include copy of this form with your communication to applicant.										